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-	3630	((dielectric or photoresist) same milling)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/02/19 11:03

-	3	6150046.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/02/19 11:27
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... Because of the very low ion **milling rate** of the aC film and the high ... The existence of electromagnetic resonances suggested that the barrier was **dielectric**. ...  
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... the interference process occurs vertically between the two interfaces of the **dielectric** thin film. ... The **milling rate** is approxi- mately 310 m/s or 0.144 m 3 /s ...  
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Improved Sample Preparation for Cross-Sectional Transmission ...

... conventional ion-milling technique due to large ion-**milling rate** differences between ... has a large pyroelectric coefficient and a low **dielectric** constant along ...  
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... Increasing the **milling rate** in the ion milling method is possible by using a ... and tungsten tungsten-oxide extrusion in the Intel Layer **Dielectric** (pictures 6-7 ...  
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... the plating area stays constant only until the surface of the **dielectric** substrate is ... and 9 J/cm<sup>2</sup>. For these two fluence levels the **milling rate** is different ...  
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... sapphire) has been used widely in the microelectronics industry for **dielectric** films and ... Ar + beam milling is very low [4]. The low **milling rate** increases the ...  
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Slurry formulation Process conditions: **Milling rate**, duration, temperature ...

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... The **milling rate** for silicon using a high beam current (approximately 6 nA) is ... between a conducting tool and workpiece immersed in a **dielectric** medium, which ...[www.iop.org/EJ/article/0960-1317/8/4/001/jm8401.pdf](http://www.iop.org/EJ/article/0960-1317/8/4/001/jm8401.pdf) - [Similar pages](#)[\[ More results from www.iop.org \]](#)Untitled... during ion milling, the carbon has a much slower **milling rate** than the Si ... glass particles coated with thin layers of metal and **dielectric** in electrorheological ...[www.mrs.org/meetings/spring97/abstract\\_book/z/z2/](http://www.mrs.org/meetings/spring97/abstract_book/z/z2/) - 50k - [Cached](#) - [Similar pages](#)-MRS-... The ion **milling rate** for sol-gel PZT was significantly faster than ... and chemical stability, electric insulation and low **dielectric** constant; permittivity is ...[www.mrs.org/meetings/fall98/absbook/AbstractBookAA.html](http://www.mrs.org/meetings/fall98/absbook/AbstractBookAA.html) - 101k - [Cached](#) - [Similar pages](#)[PDF] The Institute of Chemical Engineers Particle Technology Subject ...File Format: PDF/Adobe Acrobat - [View as HTML](#)... the drying process, powder properties have been examined; **dielectric** (loss factor ... milling results are quantified using the concept of **milling rate** constant (K ...[www.shaf.ac.uk/ptf5/ya\\_abstracts.pdf](http://www.shaf.ac.uk/ptf5/ya_abstracts.pdf) - [Similar pages](#)Vol.61, No.1... results showed that, when material with a relatively large **dielectric** loss factor ... machine for rice-assay, which has high accuracy of **milling rate** and milling ...[bipren.en.a.u-tokyo.ac.jp/JSAM/english/journal/abstracts/61e-abstracts.htm](http://bipren.en.a.u-tokyo.ac.jp/JSAM/english/journal/abstracts/61e-abstracts.htm) - 100k - [Cached](#) - [Similar pages](#)[PDF] Emerging Gallium Nitride Based DevicesFile Format: PDF/Adobe Acrobat - [View as HTML](#)... Although piezoelectric constant for InN has not been reported, its dependence on the **dielectric** constants suggests that this constant would have a value of ...[www.engineering.vcu.edu/fac/morkoc/learning/ieee\\_gan\\_726\\_96.pdf](http://www.engineering.vcu.edu/fac/morkoc/learning/ieee_gan_726_96.pdf) - [Similar pages](#)[PDF] (Poster abstracts)

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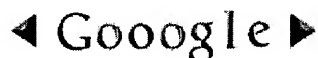
... be deposited. The sharp and straight step edge can be fabricated because of the low ion-**milling rate** of the DLC film. The fabricating ...

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... thin film element made of semiconductor material, conductive material, **dielectric** material or ... layer made of nickel-iron alloy which has a **milling rate** equal to ...

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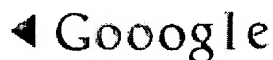
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... equal to  $V_{Nb}(\theta)$ , where  $V_{Nb}(\theta)$  is the **milling rate** and  $\theta$  ... After soaking in acetone to remove **photoresist**, the substrates were laid into the chamber ...[www.iop.org/EJ/article/0960-1317/14/1/301/jm4101.pdf](http://www.iop.org/EJ/article/0960-1317/14/1/301/jm4101.pdf) - [Similar pages](#)**[PDF] Microprocessing at the fingertips**

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... A single layer of thick ( $\sim 7 \mu\text{m}$ ) **photoresist** proved to be an effective mask under these conditions. Page 12. CHAPTER 1 INTRODUCTION 1.1. ...

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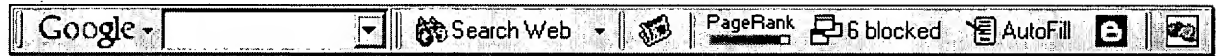
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